

CLAIMS

5 1. A vacuum processing apparatus comprising a vacuum chamber, at least one vacuum pump, a pipe connecting said vacuum chamber to said vacuum pump for evacuating said vacuum chamber, a flexible pipe included in a part of said pipe, and a mechanism for fixing said flexible pipe so as not to shrink at the time of evacuation.

10 2. A vacuum processing apparatus according to claim 1, wherein said mechanism for fixing said flexible pipe so as not to shrink at the time of evacuation fixes the vacuum pump side of said flexible pipe.

15 3. A vacuum processing apparatus according to claim 1, wherein said mechanism is arranged in a pipe extending from said vacuum pump.

20 4. A vacuum processing apparatus according to claim 3, wherein said at least one vacuum pump comprises a plurality of vacuum pumps, said mechanism includes a member fixed to the pipes extending upward from said vacuum pumps, and said member is a long member extending over said plurality of the vacuum pumps.

25 5. A vacuum processing apparatus according to claim 1, wherein said vacuum chamber includes a device for reading an alignment mark of a substrate in the vacuum.

6. A vacuum processing apparatus according to claim 5, wherein said substrate comprises a substrate of a display device.

30 7. A vacuum processing apparatus according to claim 1, wherein said apparatus is a substrate bonding apparatus of a liquid crystal display device.